

**AMENDMENTS TO THE CLAIMS:**

The following listing of claims replaces all prior versions and listings of claims in the application. Please amend claims 1 and 12, as follows:

1. (Currently Amended) A plasma etching method for implementing a specific etching process on a workpiece placed on an electrode provided within a processing chamber by introducing a processing gas into said processing chamber, generating plasma inside said processing chamber with a plasma source and applying biasing power to said electrode, wherein;

an etching step in which the workpiece is etched over a specific length of etching time by applying the biasing power to said electrode and a film formation step in which a protective film is formed as an etching mask at a surface of the workpiece over a specific length of film formation time while the biasing power is decreased or cut off are sequentially repeated, with the ~~lengths of individual etching times and individual film formation time being times adjusted to be~~ increased relative to the length of etching time as the etching process progresses.

2. (Original) A plasma etching method according to claim 1, wherein:

the lengths of the film formation times are extended relative to the extent to which the etching process has progressed.

3. (Original) A plasma etching method according to claim 1, wherein:

the lengths of the film formation times are set at 1 second or longer.

FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER LLP

1300 I Street, NW  
Washington, DC 20005  
202.408.4000  
Fax 202.408.4400  
www.finnegan.com

4. (Original) A plasma etching method according to claim 1, wherein:  
said etching step is implemented as a final step of said etching process.

5. (Original) A plasma etching method according to claim 1, wherein:  
said film formation step is implemented as a first step of said etching process.

6. (Original) A plasma etching method according to claim 1, wherein:  
the etching target is a silicon oxide film; and  
said processing gas is constituted of a gas containing fluorocarbon gas.

Claims 7-11 (Canceled).

12. (Currently Amended) A plasma etching method according to claim 1,  
wherein the length of etching time is ~~relatively~~ decreased relative to the film formation  
time as the etching process progresses.

FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER <sup>LLP</sup>

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